



# Raman Microscopy with High Spatial Resolution for Semiconductor Applications

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SOL instruments Ltd. (SOLAR TII) was founded in 1994.

SOL instruments Ltd. is an innovation-focused manufacturer of technologically advanced instruments for

- Analysis
- Spectroscopy
- Lasers

SOL instruments Ltd. continually expands its presence on the world market of high-end products.  
The products are currently exported to over 30 countries.

# Confotec family



Confotec® MR150



Confotec® MR350



Confotec® MR520

Confotec® NR500



Confotec® CARS



## 3D Raman Microscopy System Confotec® NR500



## Features

- 3D Raman Confocal Measurements
- Laser Reflection Measurements (1000x1000 pixels per 3 sec)
- Fully automated control
- Completely motorized laser change (up to 3 / 5 lasers)
- High spatial resolution (lateral: up to 200 nm; axial: up to 500 nm)
- High spectral resolution (up to 0.006 nm)
- Wide spectral range
- High temporal and temperature stability

## Applications

### Advantage of Raman Spectroscopy

- Qualitative and Structural material analysis
- No special requirements for sample preparations
- Nondestructive, non contact method
- Very small sample can be measured
- Depth analysis

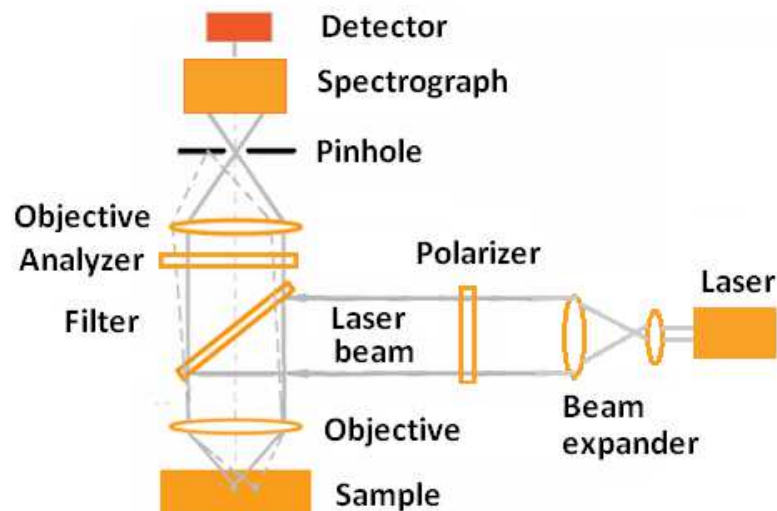
### Application field

- Pharmaceutical
- Material science
- Bioscience
- Geological
- Heritage and Art
- Organic and Polymer chemistry
- Forensic science, etc.

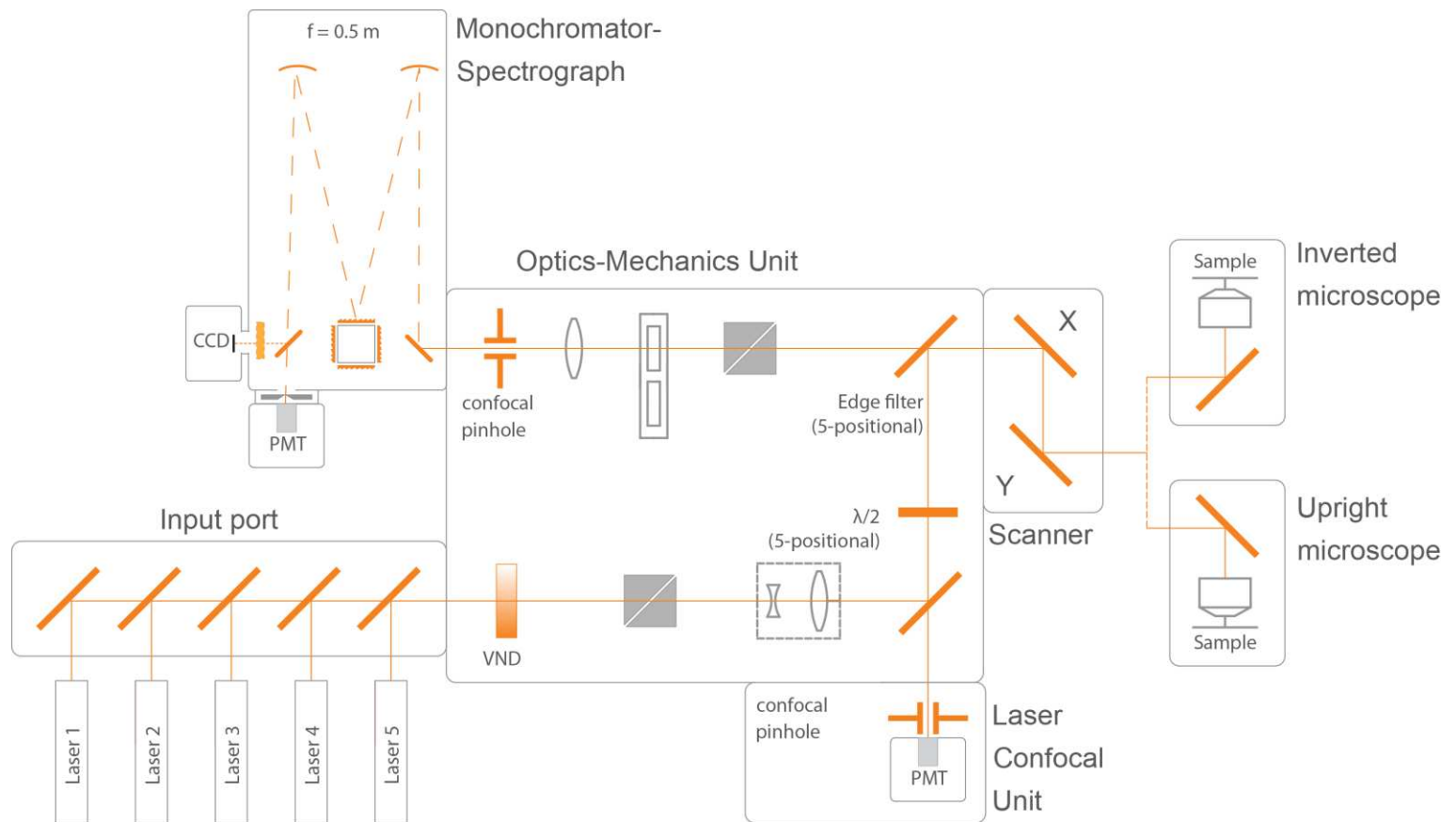


## Confocal Raman Microscopy. Principles.

A pinhole blocks the scattered light which is coming from the out-of-focus points.



## Confotec® NR500 Optical Setup





## High sensitivity for Raman spectra detection

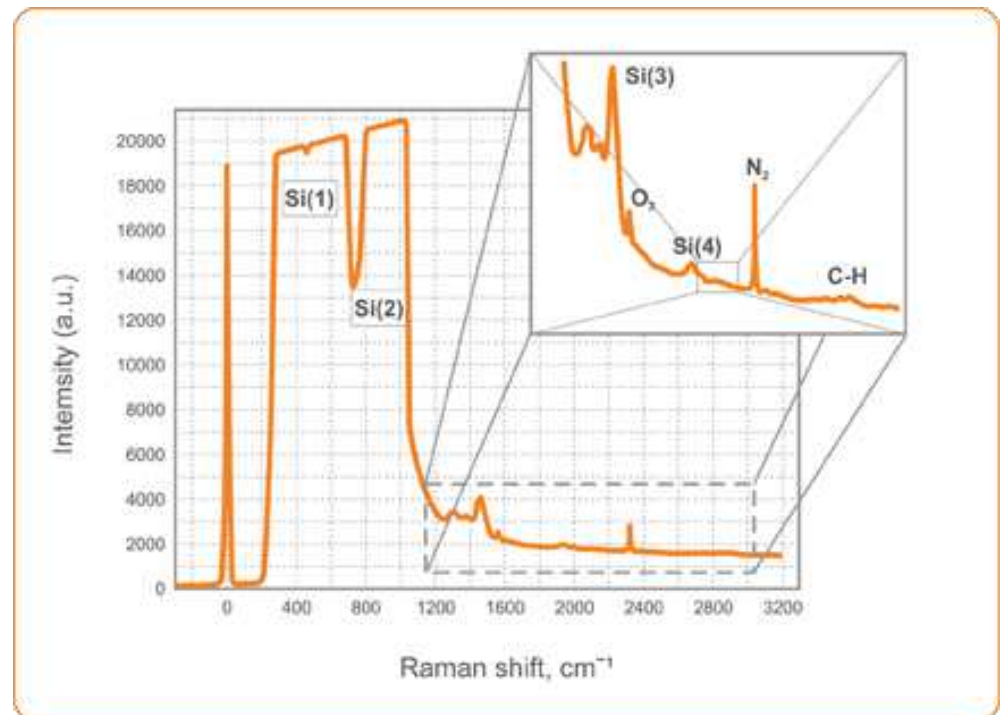
Raman spectrum of Si wafer.

Si (4) peak is clearly detected.

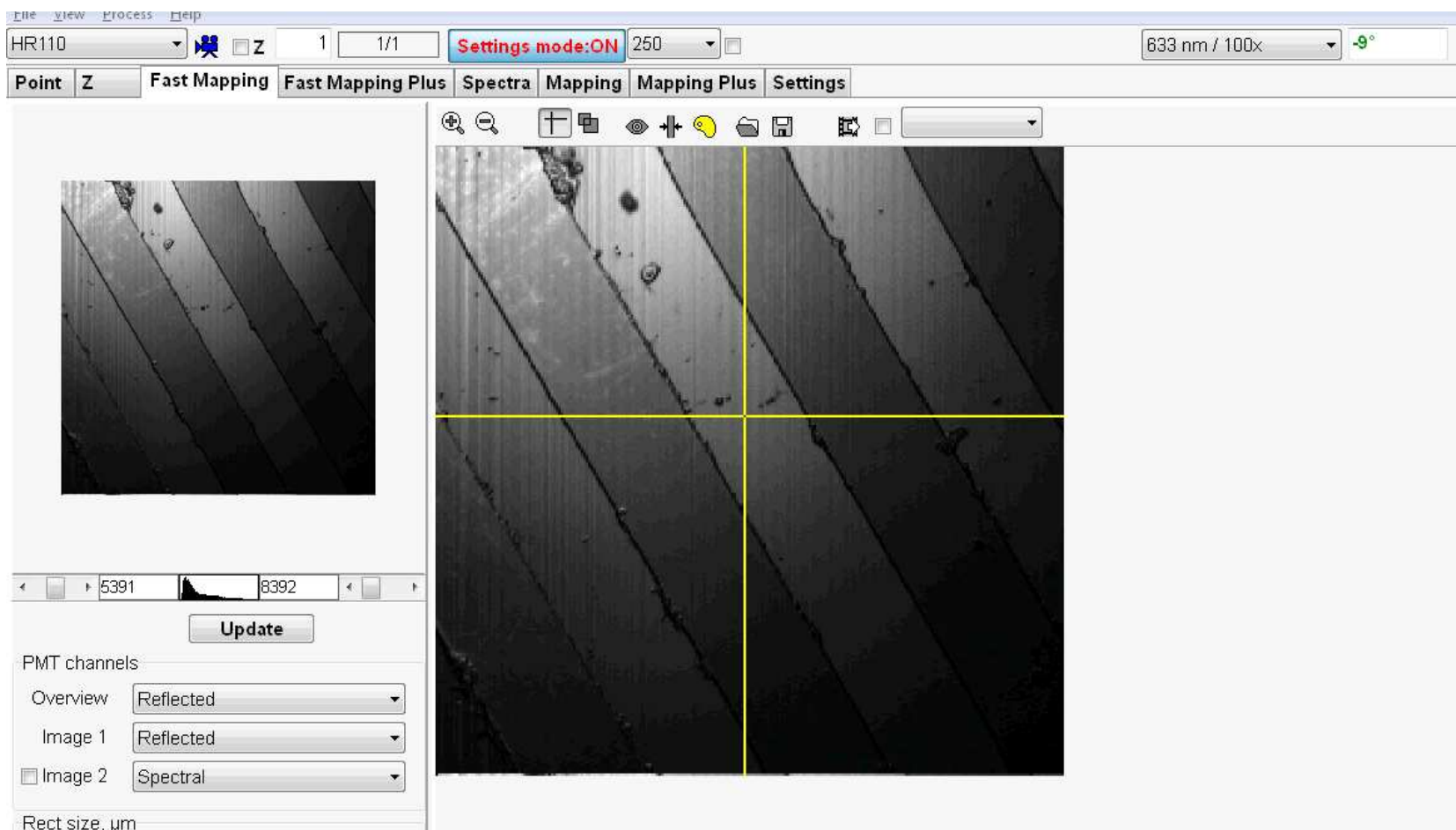
Si (1) and Si (2) are in deep saturation.

Accumulation time - 60 seconds.

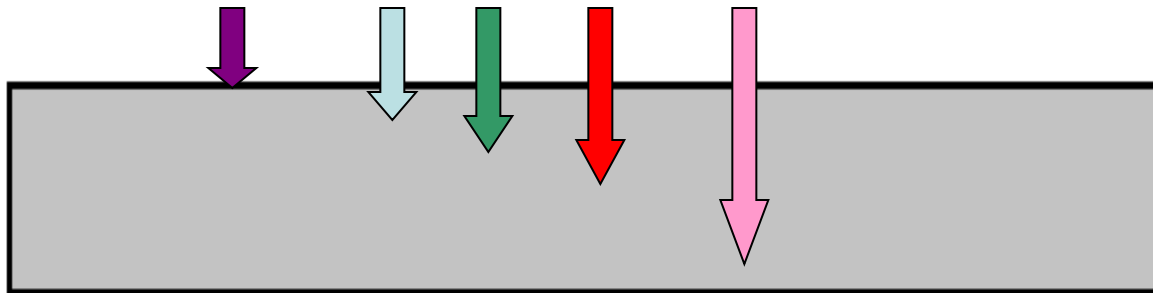
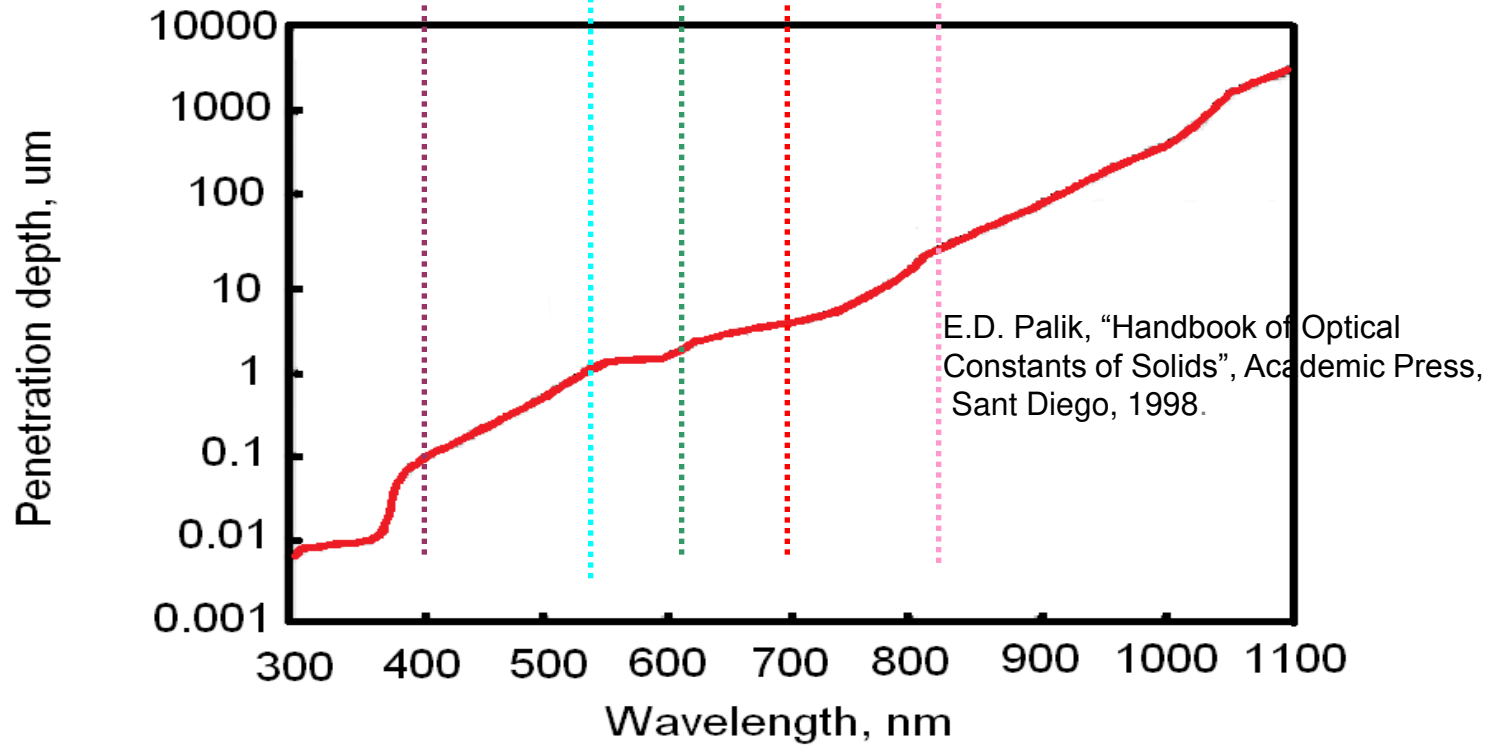
488 nm laser, 5 mW power



## High speed Raman imaging with Confotec®

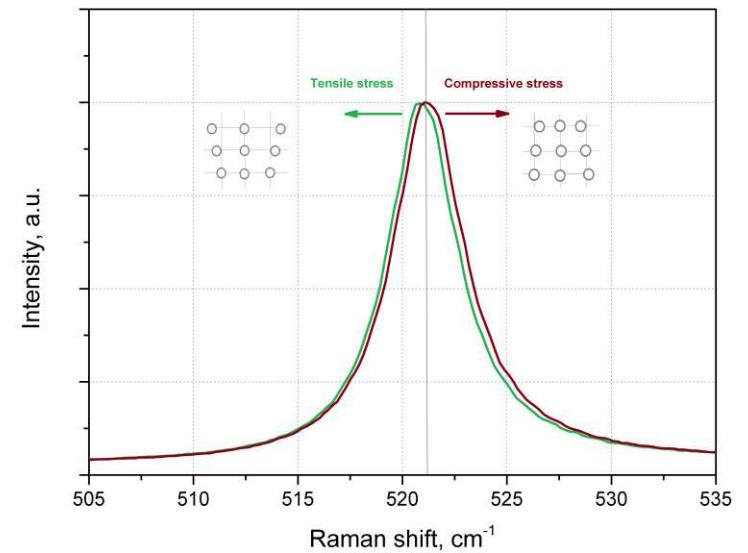
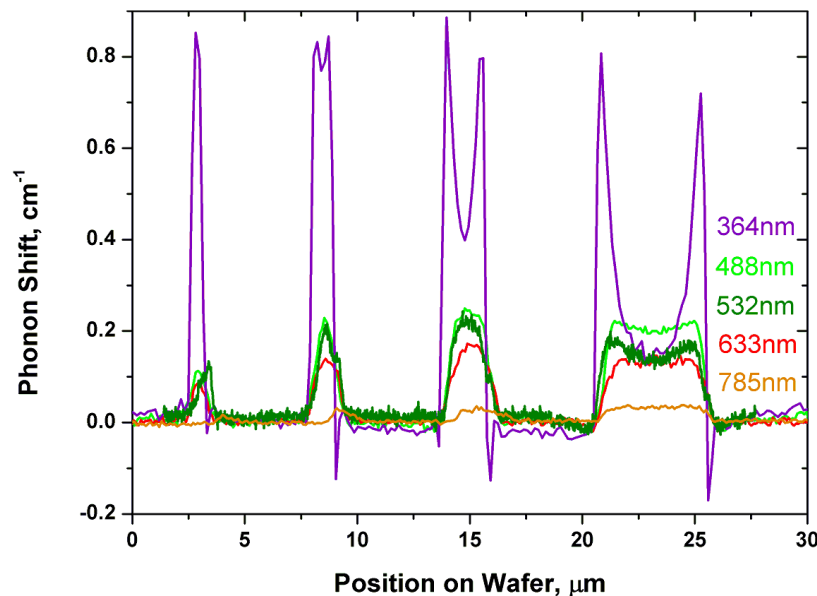


Many lasers can be installed



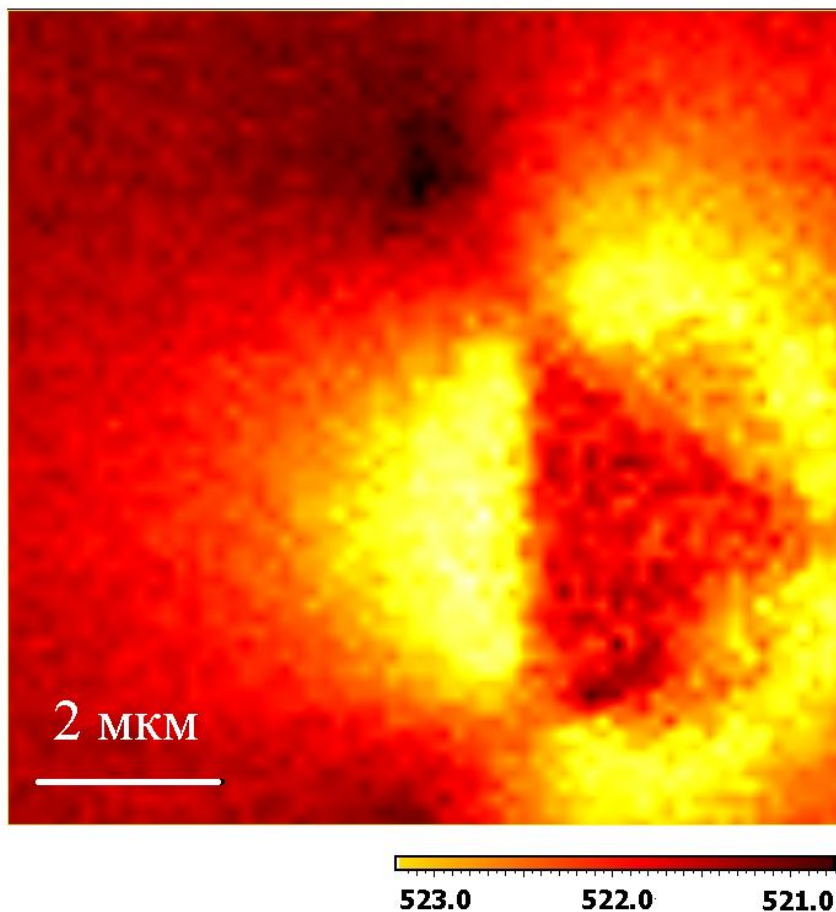
The next equation can be applied to the Si stress monitoring:

$\sigma(\text{MPa}) = -435 \cdot (\omega - \omega_0) (\text{cm}^{-1})$ ,  
 where  $\sigma$  is the stress value,  
 $\omega_0 = 520.5 \text{ cm}^{-1}$  is the peak position  
 of the stress-free state,  $\omega$  is the Si  
 peak position at the stressed state.



The sample consists 1, 1.5, 2 and 4  $\mu\text{m}$  wide Si stripes separated by 4  $\mu\text{m}$  shallow trenches.

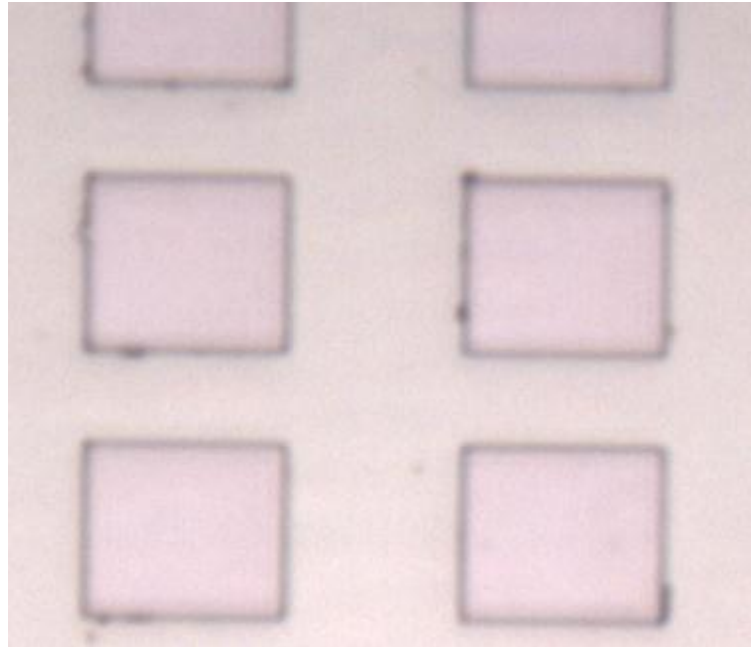
Raman image (peak position)

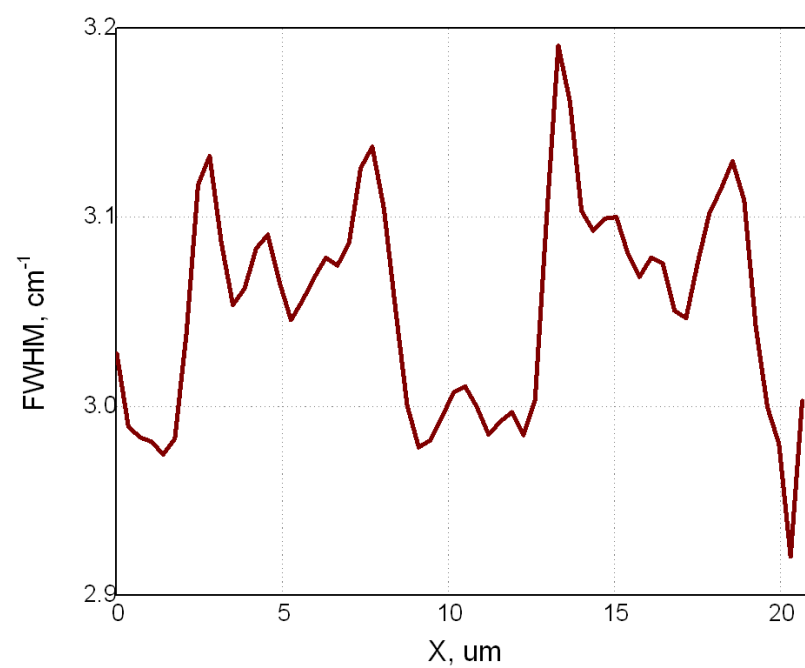
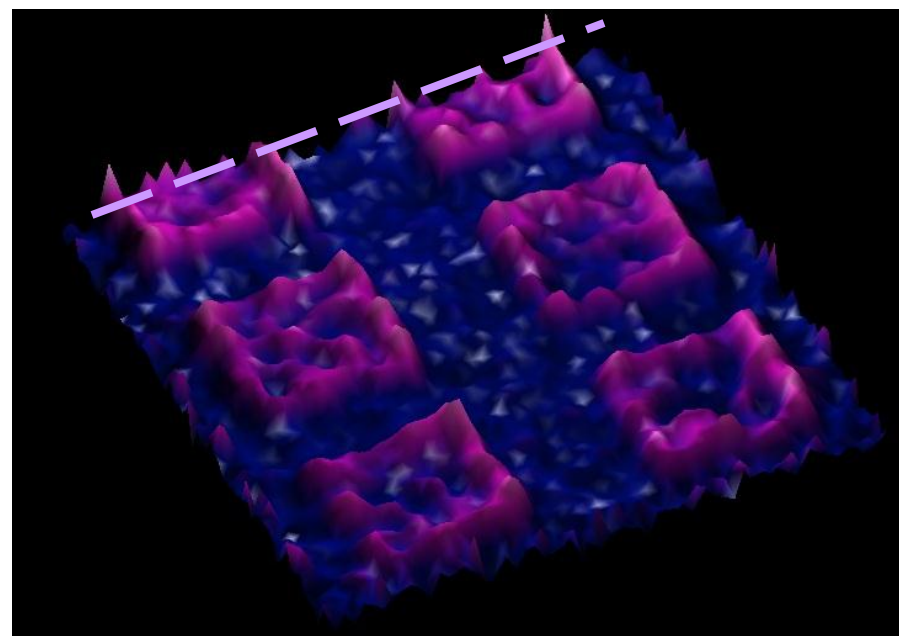
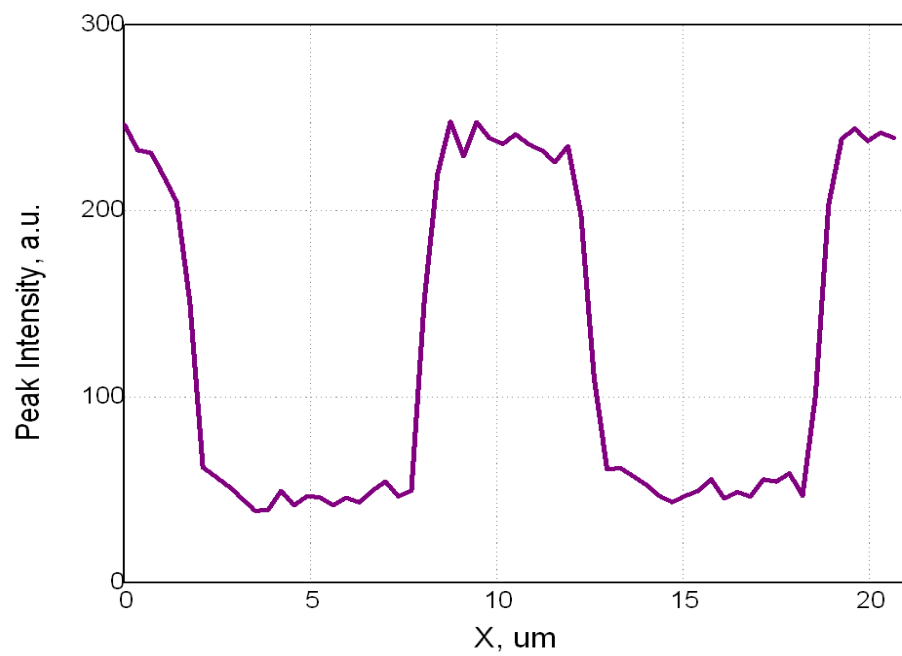
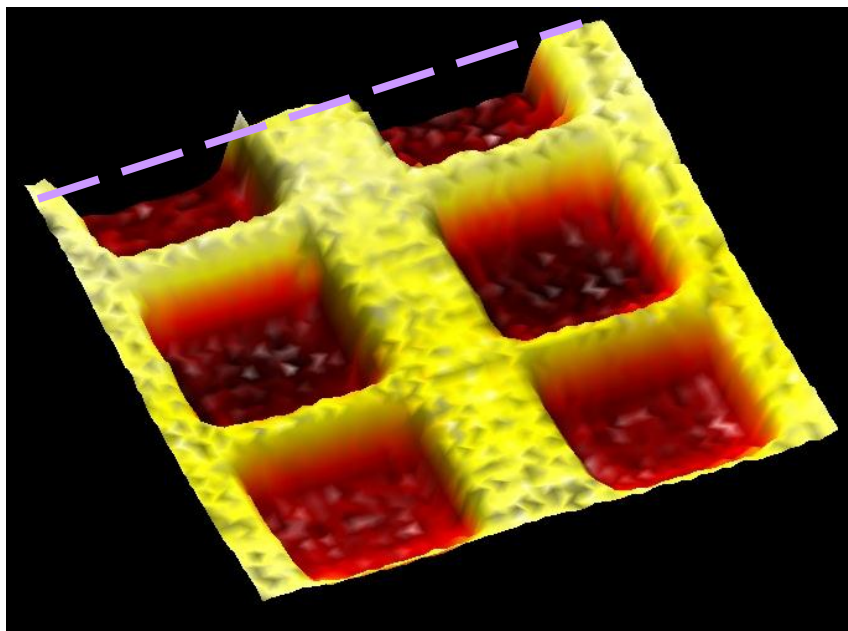


Optical image

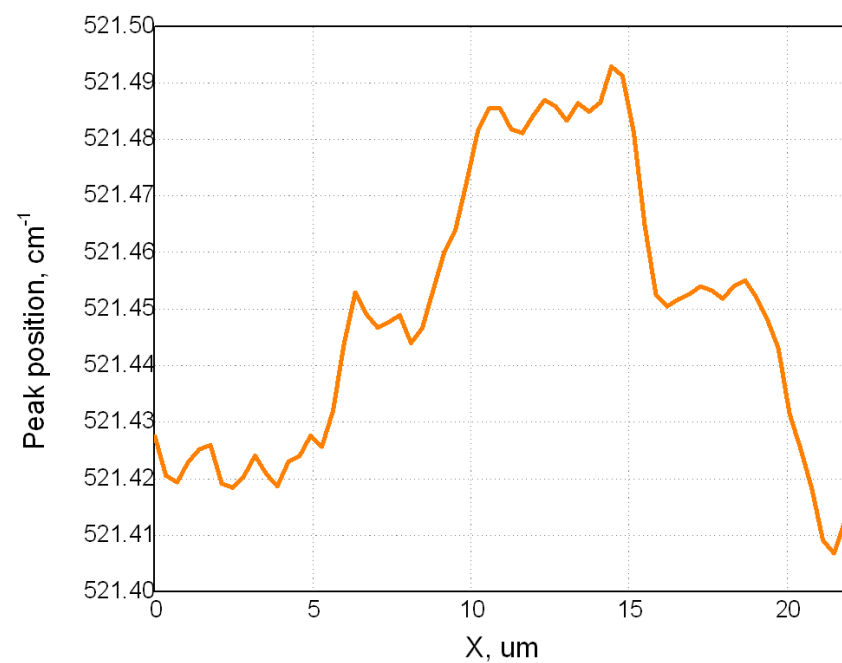
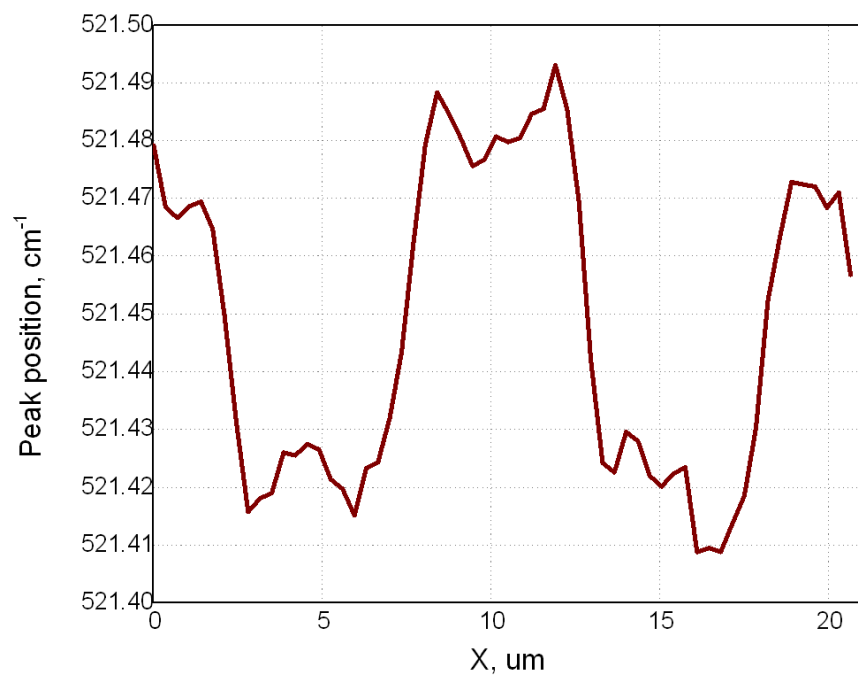
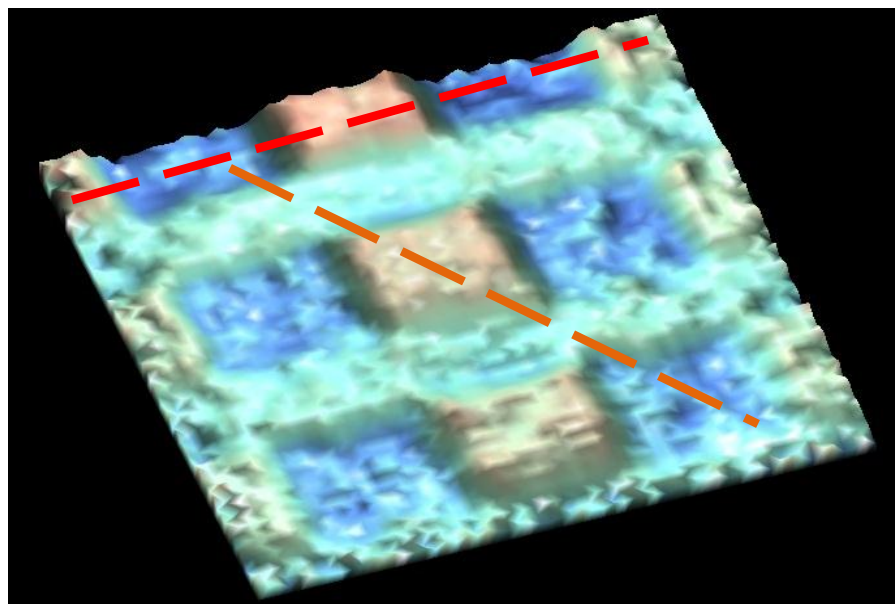


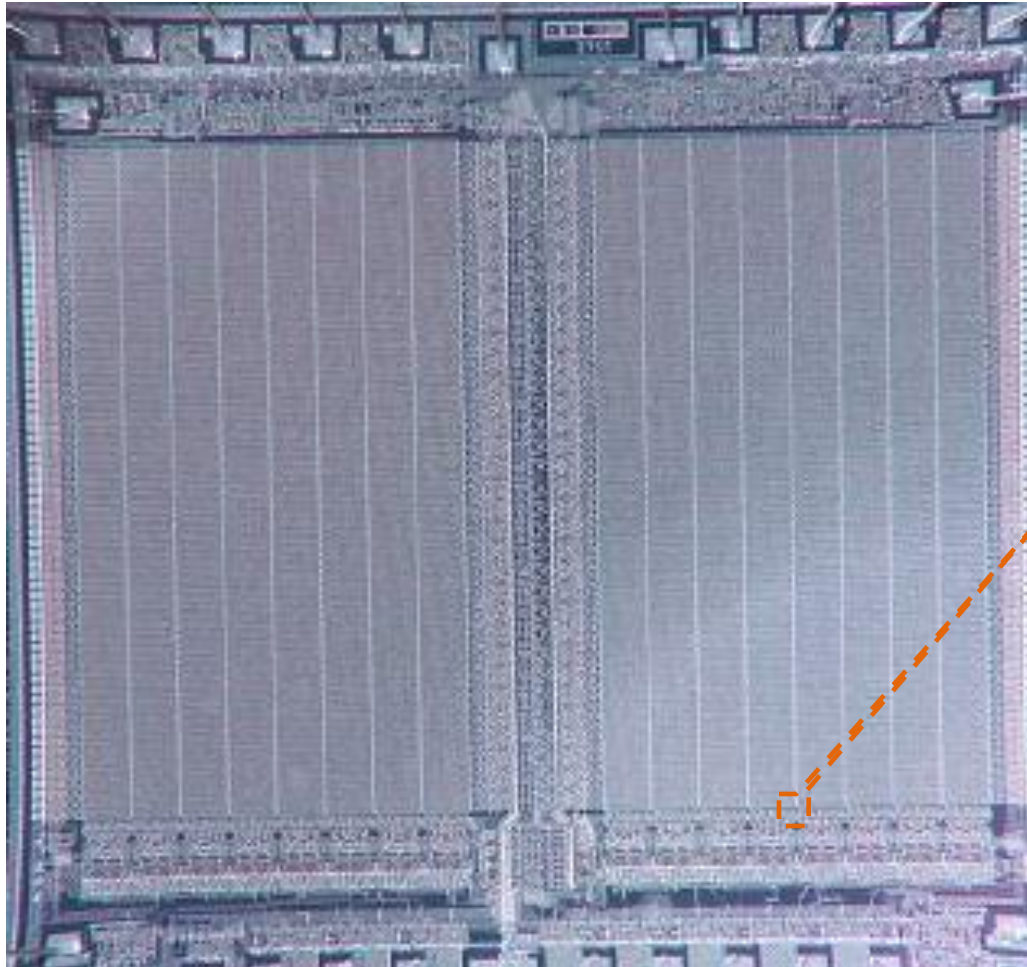
Structured Si sample. Optical image (100x)







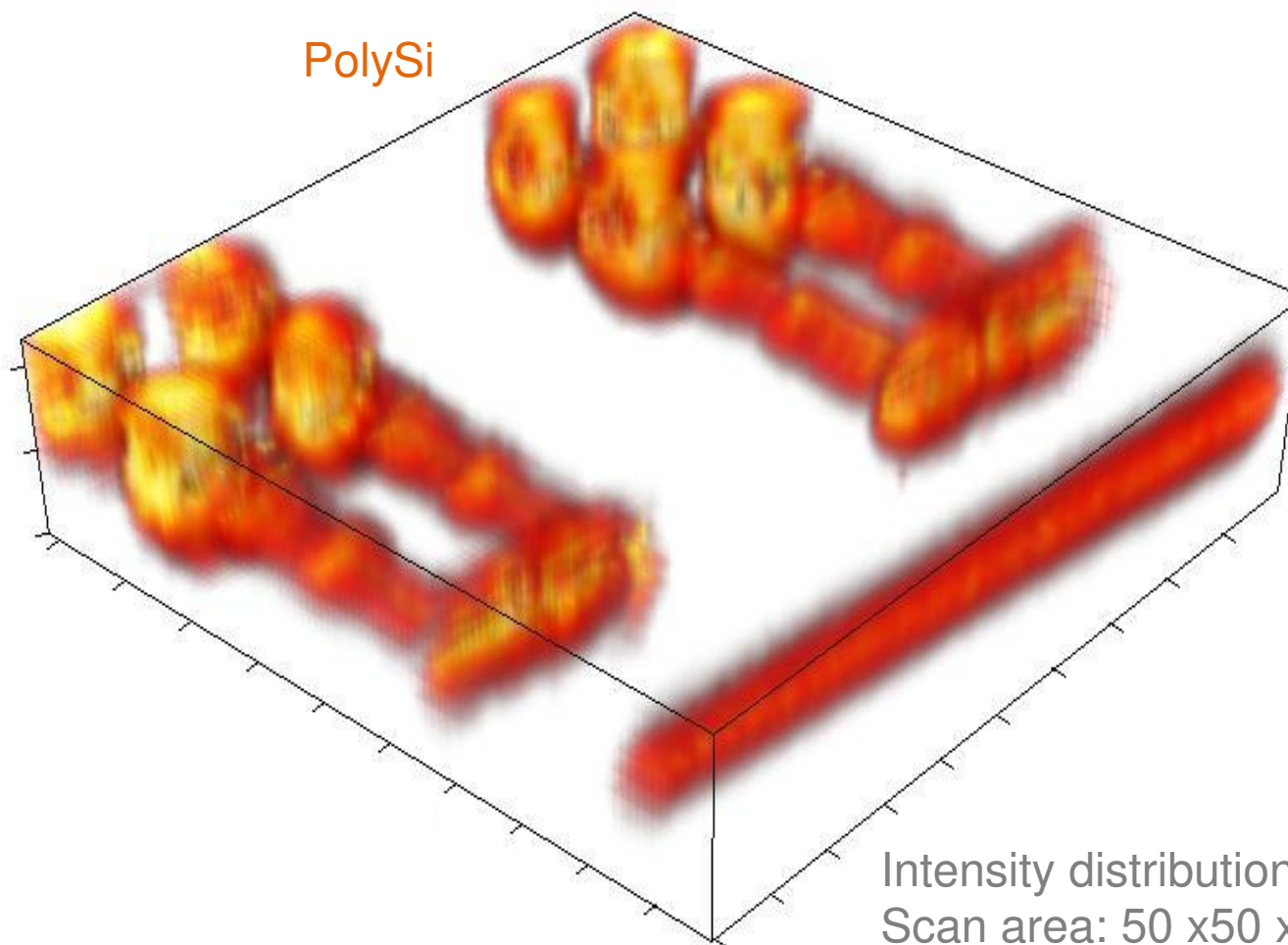




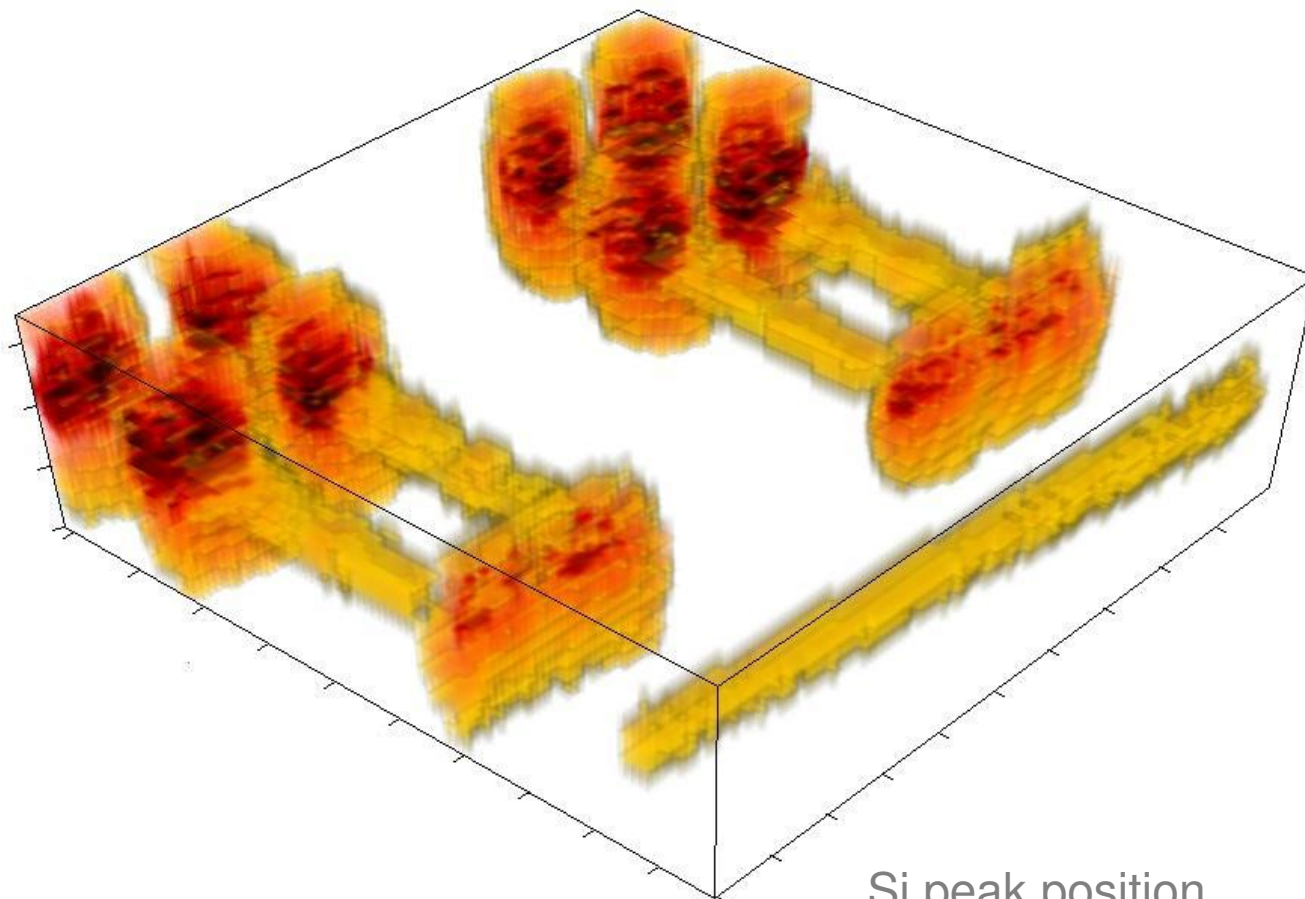
5x



100x



Intensity distribution (Si peak)  
Scan area: 50 x 50 x 7  $\mu\text{m}$   
Points: 100 x 100 x 10  
Time per point: 0.1 sec



Si peak position  
Scan area: 50 x 50 x 7  $\mu\text{m}$   
Points: 100 x 100 x 10  
Time per point: 0.1 sec

## Ge QD on a Silicon substrate

Self-assembled Ge dots grown on Si substrates are attracting attention because they have a potential to be simply integrated with the existing Si-based technology.

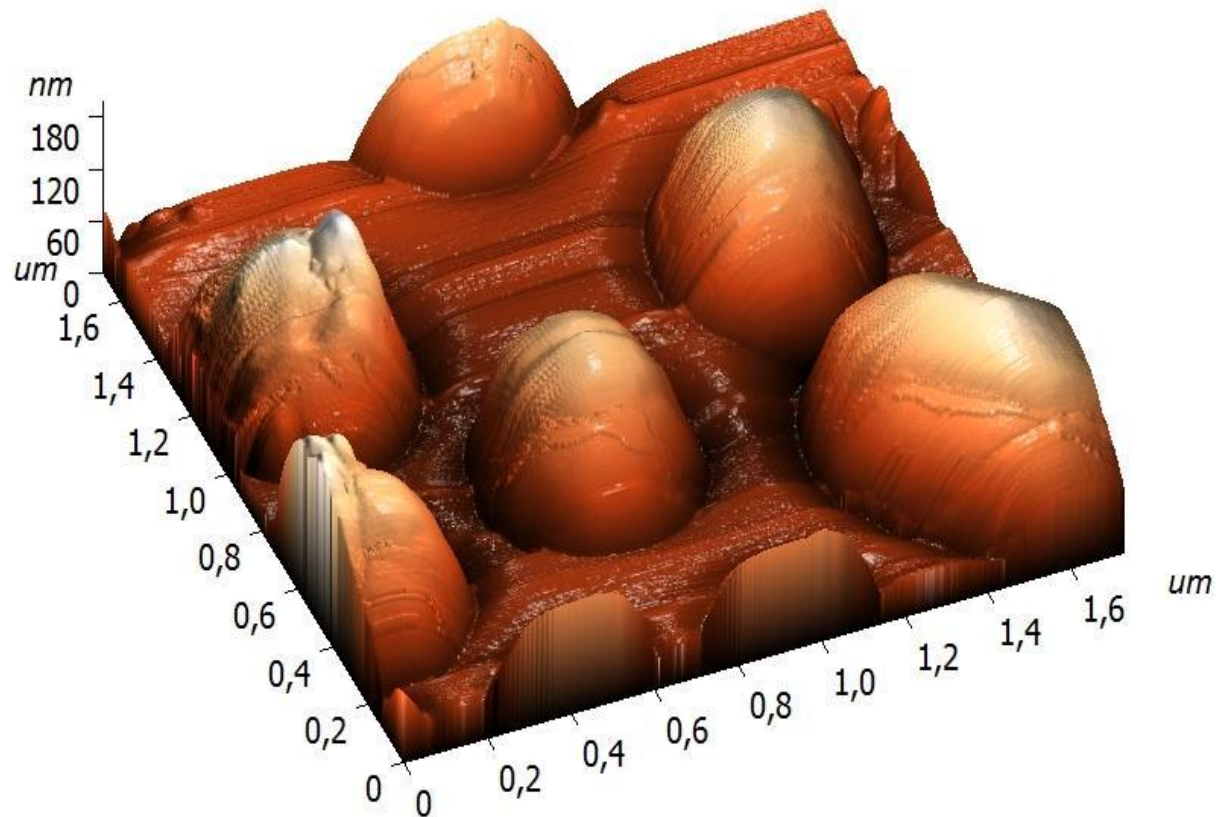
The electronic properties of the Ge dots depend on many parameters, including shape, size and distribution of strain.

Raman scattering spectroscopy is absolutely necessary method for the characterization of QDs.

Raman spectroscopy allows to obtain information on the composition, strain in the structures, distribution of dots on the surfaces.

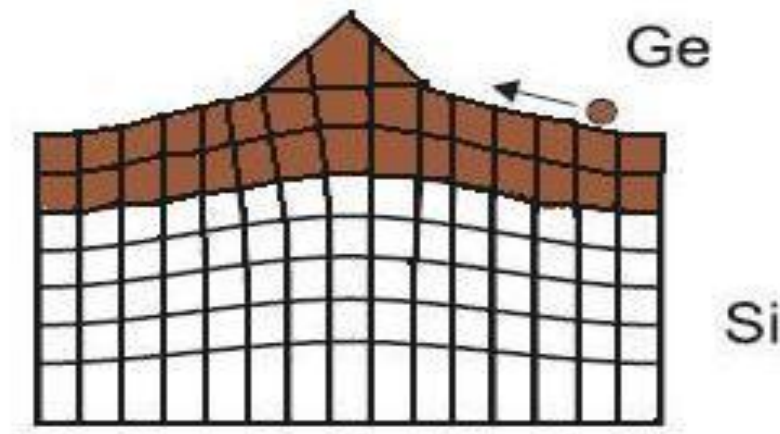


## AFM Topography



## Ge QD on a Silicon Substrate

Forming of three-dimensional Ge islands on Si substrate is illustrated below.



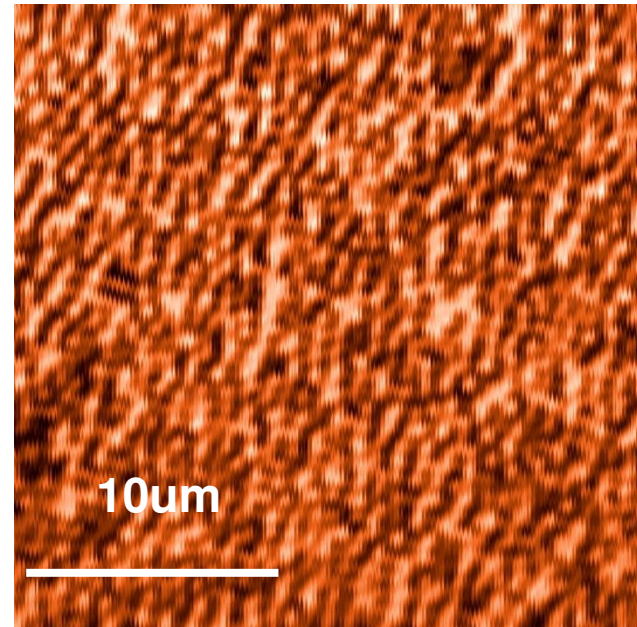
Growing of Ge dots on Si substrate (schematic diagram)



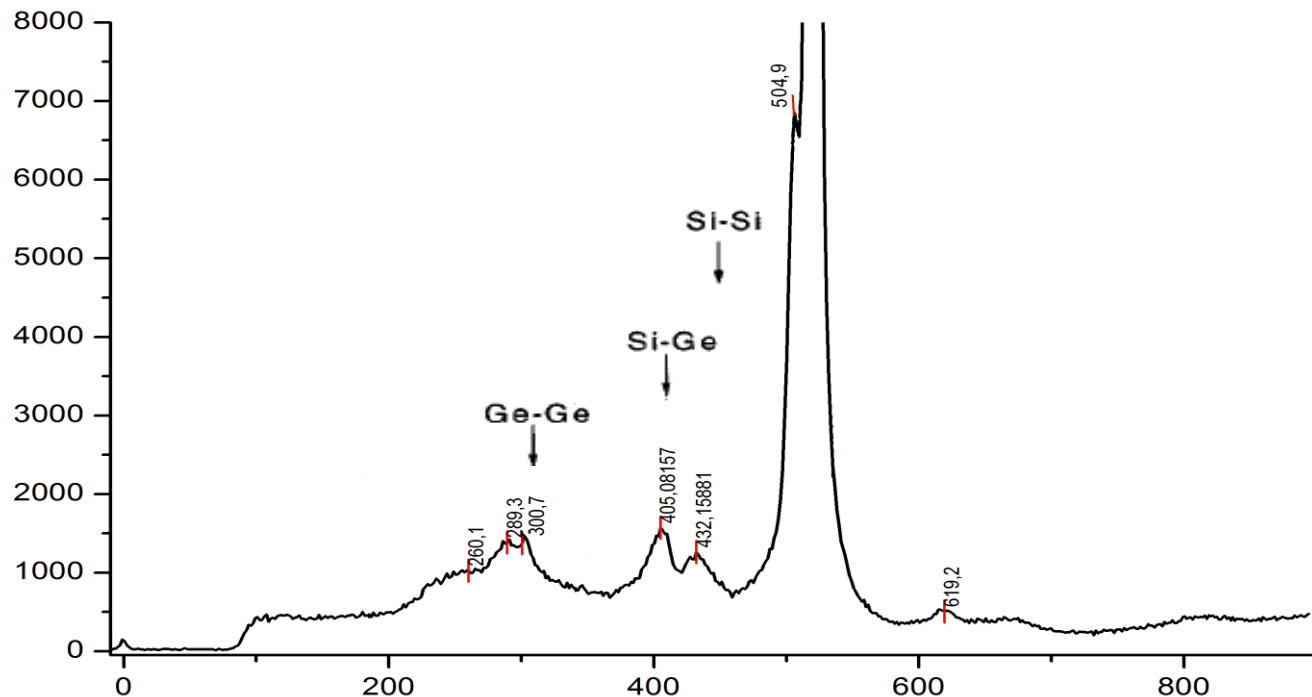
Optical image, 100x objective



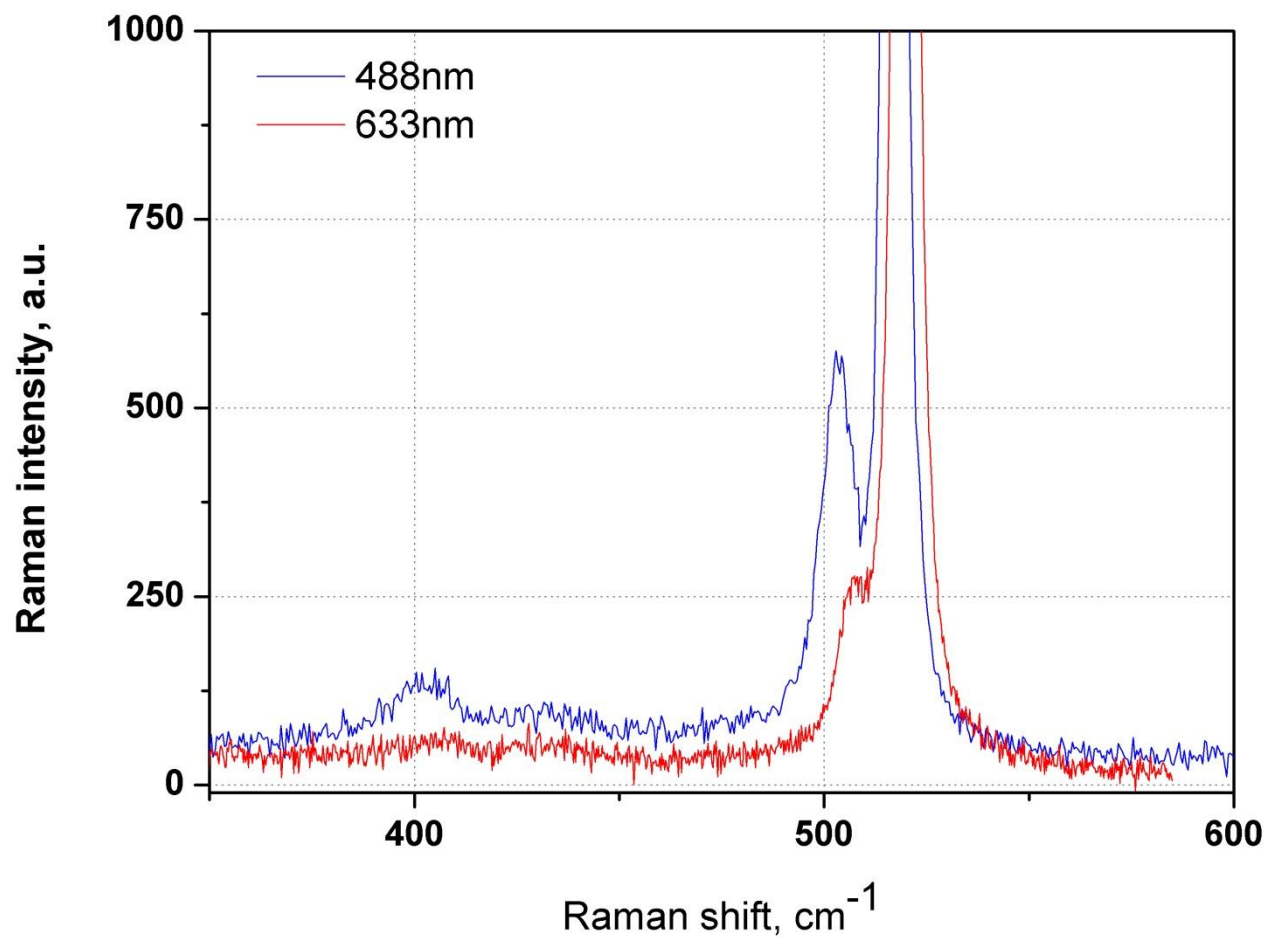
Rayleigh scattering, 21x21um, 488 nm

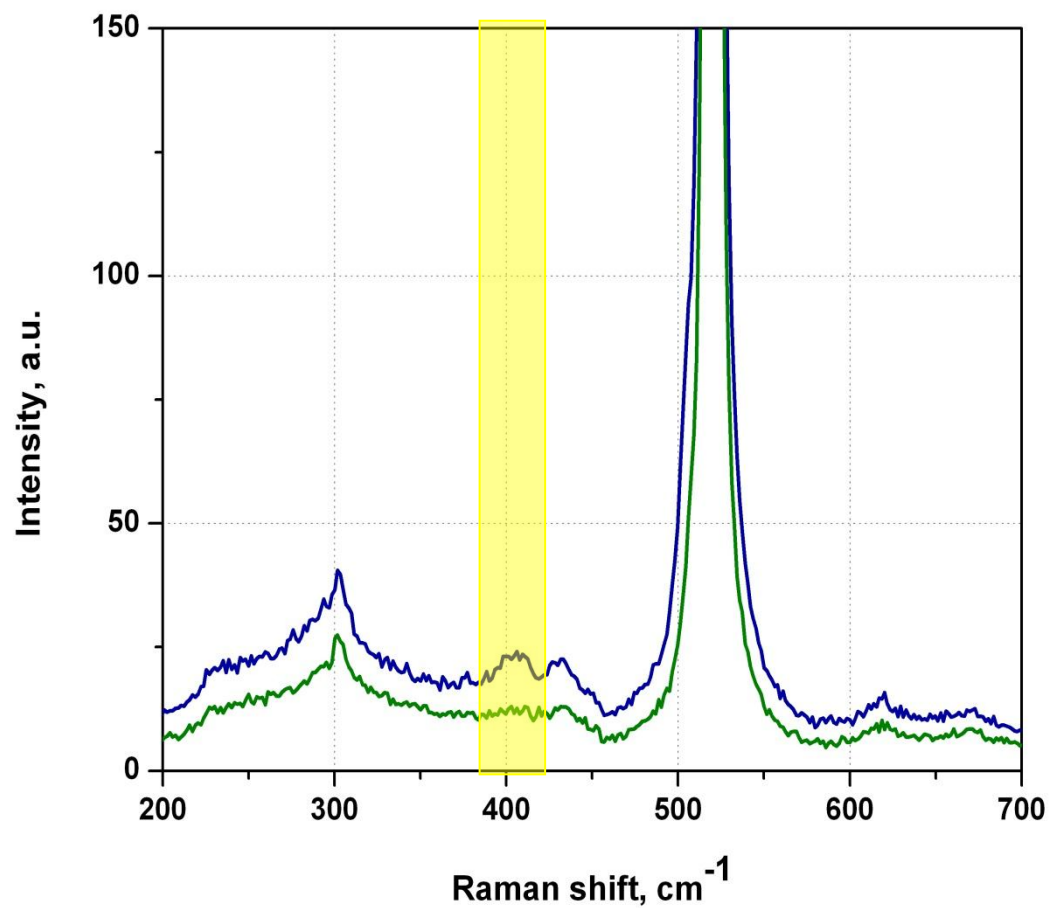


## Raman Spectrum of Ge dots on Si

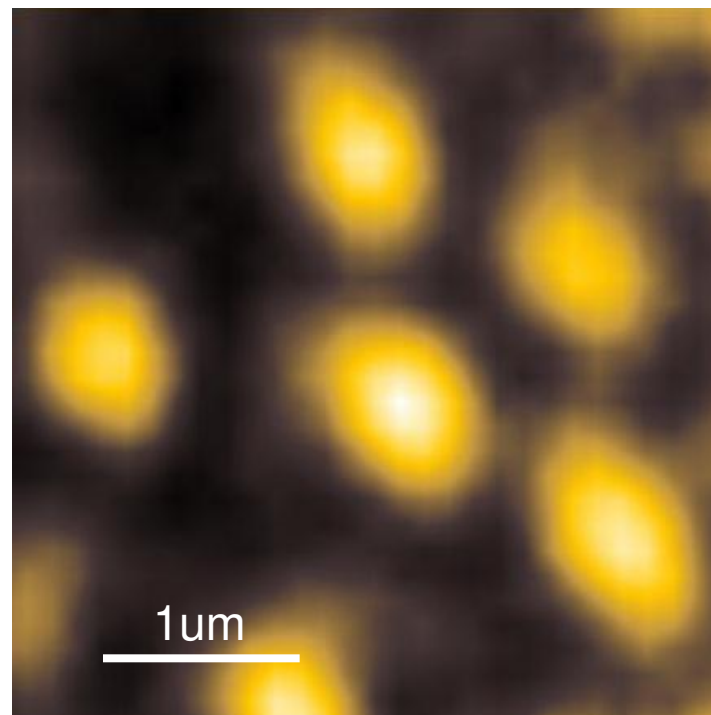


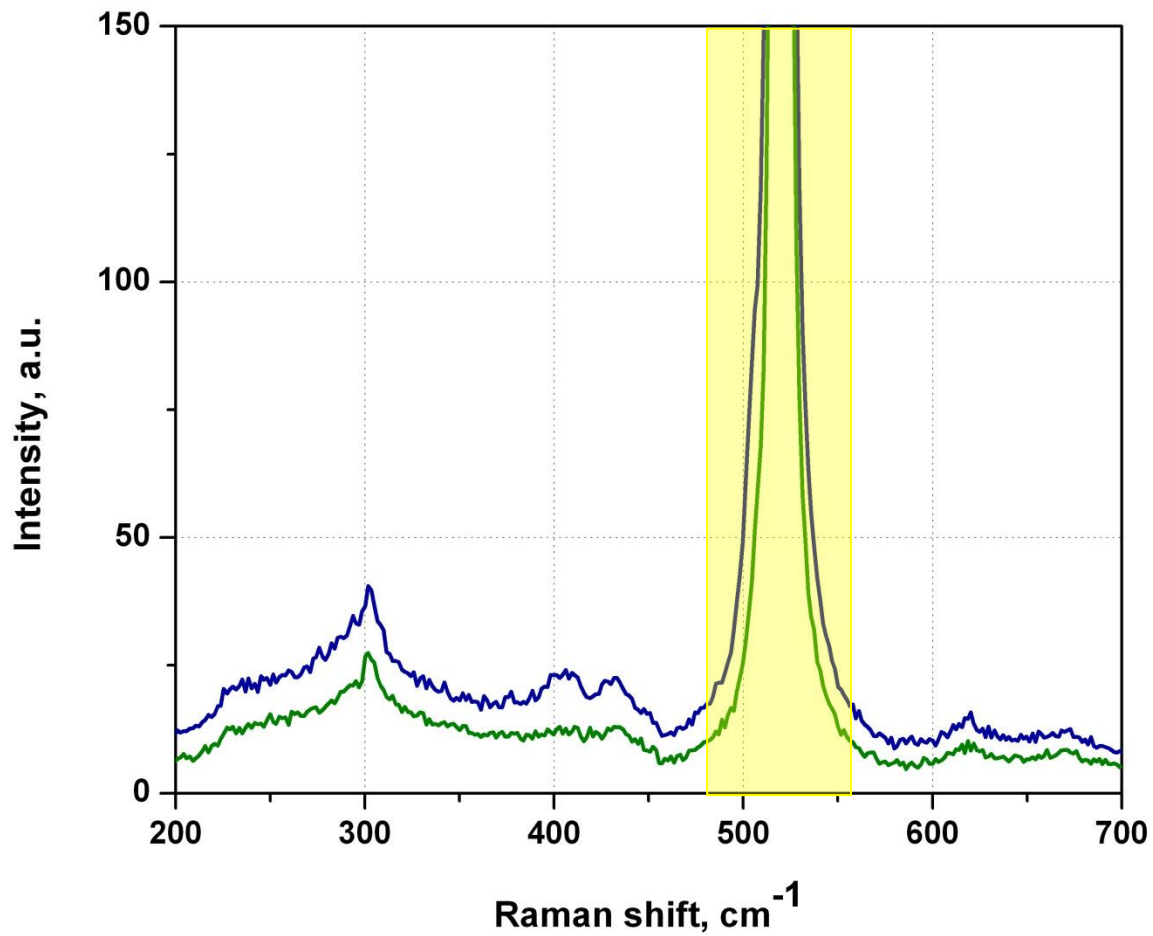
Samples exhibit two strong bands at 504.9  $\text{cm}^{-1}$  and 521  $\text{cm}^{-1}$ , and many weak features. Ge-Ge, Si-Ge and Si-Si optical modes can be found at around 290, 405 and 432  $\text{cm}^{-1}$ , respectively.



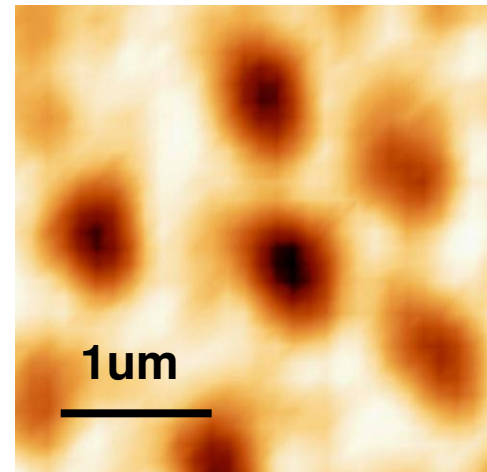


Peak intensity

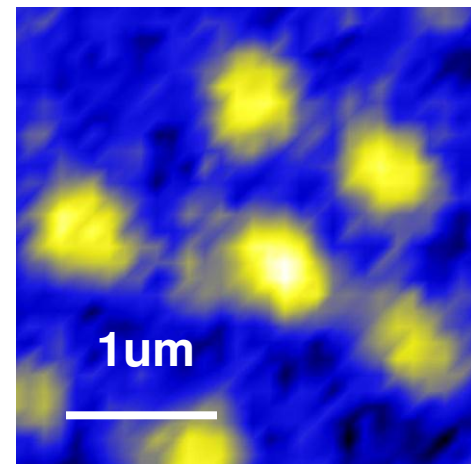




Peak position



Peak FWHM



Chen et al, Physical review B, Volume 65, 233303

$$\begin{aligned}\omega_{\text{SiGe}} &= 400.5 + 14.2x - 575\varepsilon & 405.08 \text{ cm}^{-1} \\ \omega_{\text{GeGe}} &= 282.5 + 16x - 385\varepsilon & 289.3 \text{ cm}^{-1}\end{aligned}$$

$\varepsilon$       Удельная деформация в структуре

$x$       содержание Ge

## SiC analysis

SiC has become important in the semiconductor industry because of its properties:

- High thermal conductivity
- High electric field breakdown strength
- High maximum current density



# Raman Scattering of Different SiC Polytypes

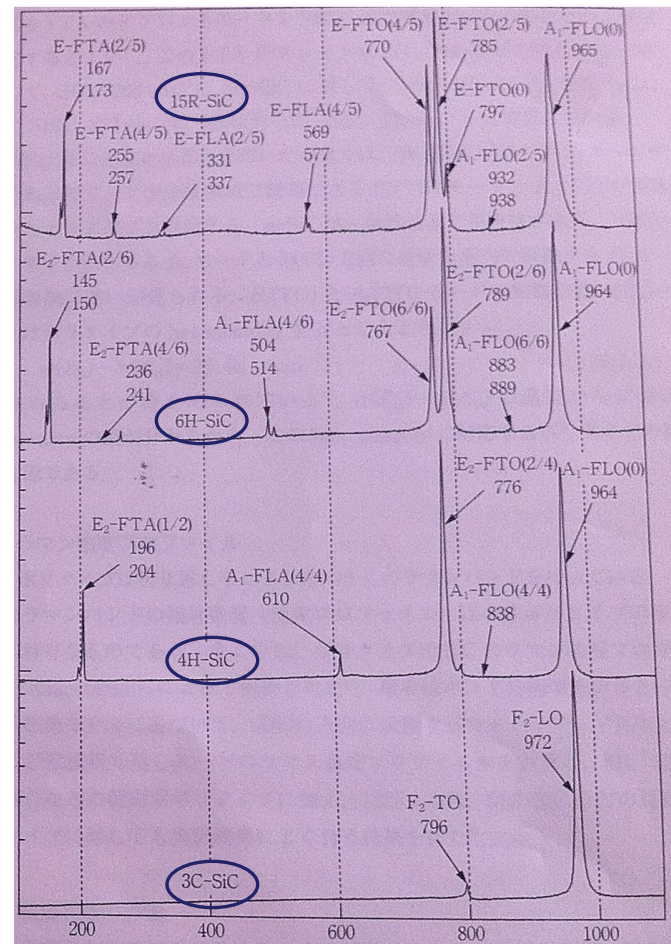
## Main Raman Bands

Polytype

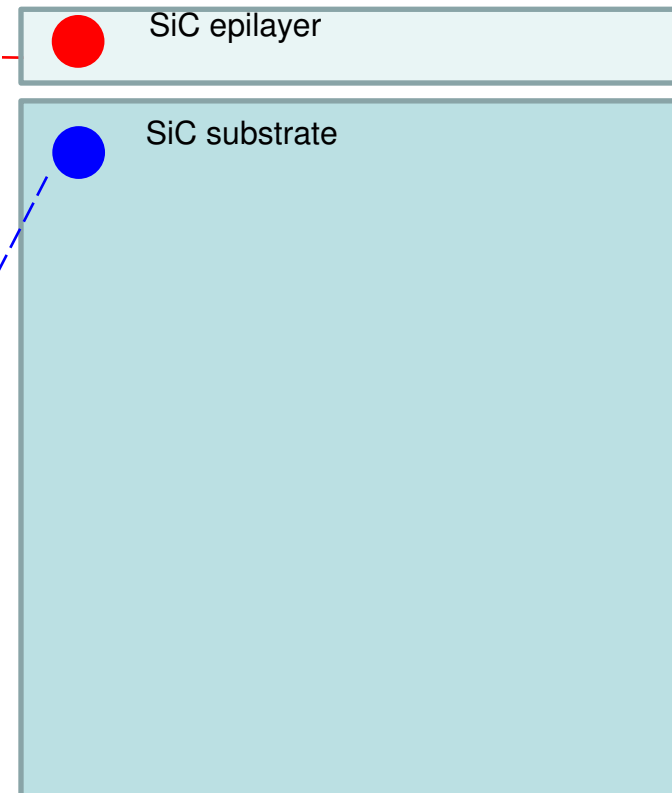
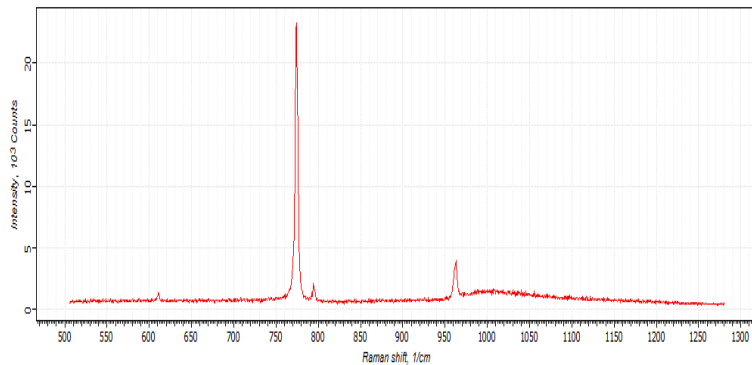
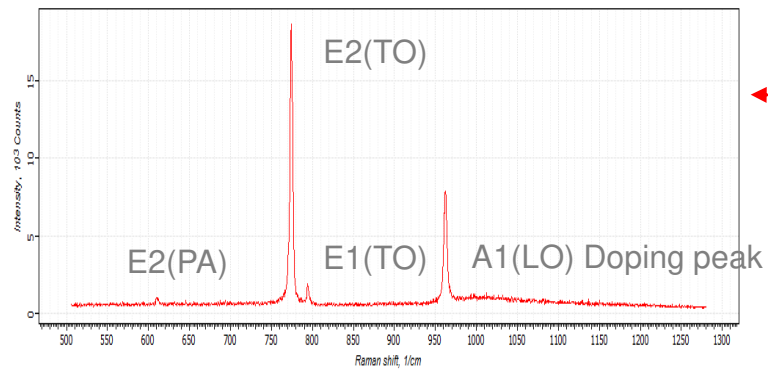
		FTA : cm <sup>-1</sup>	FTO : cm <sup>-1</sup>	FLA : cm <sup>-1</sup>	FLO : cm <sup>-1</sup>
3C	T <sub>d</sub> <sup>2</sup>	-	796 (F <sub>2</sub> )	-	972 (F <sub>2</sub> )
2H	C <sub>6v</sub> <sup>4</sup>	264 (E <sub>2</sub> )	799 (E <sub>1</sub> ) 764 (E <sub>2</sub> )	-	968 (A <sub>1</sub> ) -
4H	C <sub>6v</sub> <sup>4</sup>	196, 204 (E <sub>2</sub> ) 266 (E <sub>1</sub> )	796 (E <sub>1</sub> ) 776 (E <sub>2</sub> )	610 (A <sub>1</sub> )	968 (A <sub>1</sub> ) 838 (A <sub>1</sub> )
6H	C <sub>6v</sub> <sup>4</sup>	145, 150 (E <sub>2</sub> ) 236, 241 (E <sub>1</sub> ) 266 (E <sub>1</sub> )	797 (E <sub>1</sub> ) 789 (E <sub>2</sub> ) 767 (E <sub>2</sub> )	504, 514 (A <sub>1</sub> ) -	965 (A <sub>1</sub> ) 889 (A <sub>1</sub> ) -

\*FTA - Folded Transversal Acoustical mode , FTO - Folded Transversal Optical mode, FLA – Folded Longitudinal Acoustical mode, FLO – Folded Longitudinal Optical mode

## Raman Spectra of Different Polytypes



## Silicon Carbide (4H-SiC)






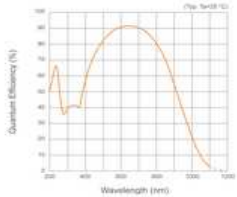
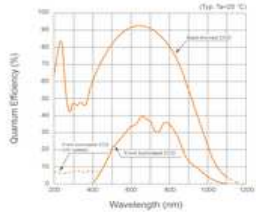
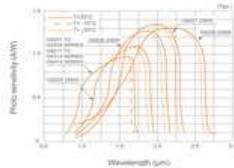
# SOL instruments® Spectrographs



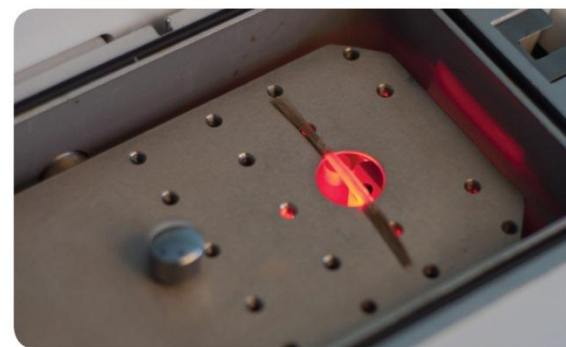
Series	<b>MS200</b> monochromator- spectrograph	<b>MS350</b> monochromator- spectrograph	<b>MS520</b> monochromator- spectrograph	<b>MS750</b> monochromator- spectrograph	<b>MSDD1000</b> monochromator- spectrograph
Photo of device:					
Optical scheme:	 Cherny–Turner	 Cherny–Turner	 Cherny–Turner	 Cherny–Turner	 Cherny–Turner
Ports:	1 input, 2 output	1 input, 2 output	1 input, 2 output	1 input, 2 output	2 input, 2 output
Wavelength range:	185 nm – 60 μm	185 nm – 60 μm	185 nm – 60 μm	185 nm – 60 μm	185 nm – 60 μm
F/number (entrance):	1/3.6	1/3.8	1/5.4	1/8.9	1/5.9
Focal length (output):	200 mm	350 mm	520 mm	750 mm	1000 mm (2 x 500)
Size of diffraction gratings:	40 x 40 x 6 mm	70 x 70 x 10 mm	80 x 70 x 10 mm	80 x 70 x 10 mm	80 x 70 x 10 mm
Stray light (20nm from laser line 632.8nm):	$3 \times 10^{-5}$	$1 \times 10^{-5}$	$1 \times 10^{-6}$	$5.5 \times 10^{-7}$	$1 \times 10^{-8}$

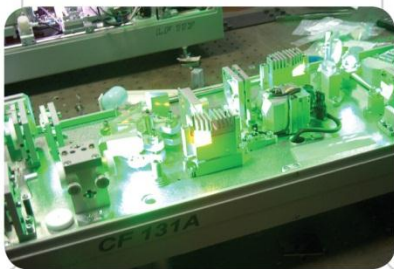
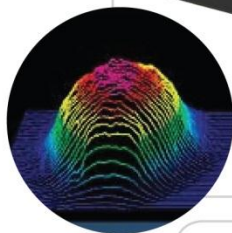
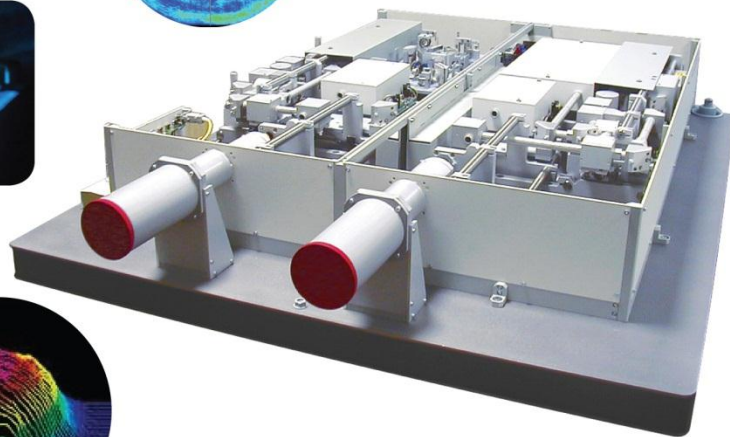
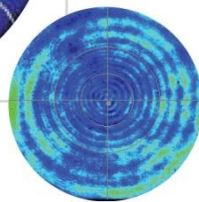
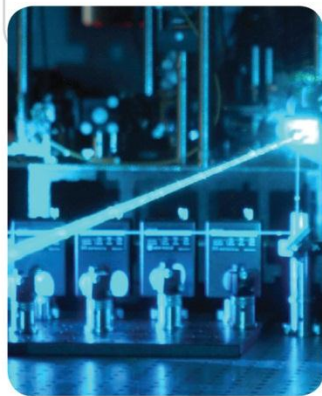
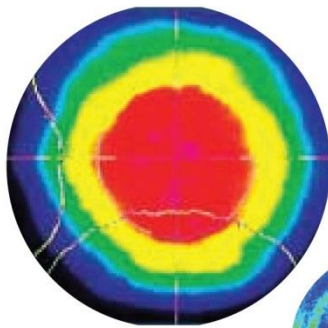
# SOL instruments® Spectral Cameras



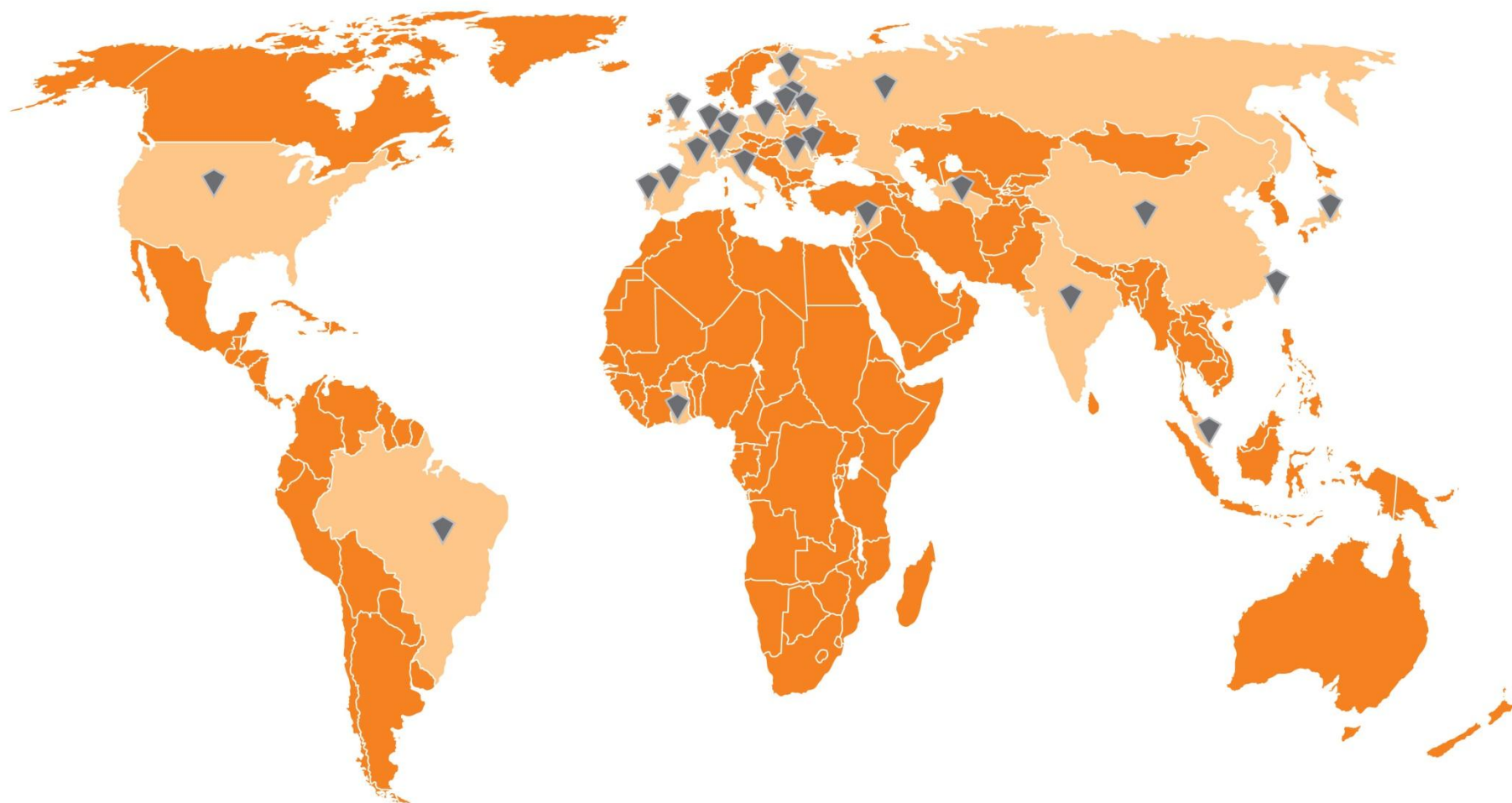
Model	HS 103H CCD area image sensor	HS 101H (HR), HS 101H CCD area image sensor		HLS 190IR Linear InGaAs detector
Photo of the device				
Spectral sensitivity				
Technical characteristics	HS 103H	HS 101H (HR)	HS 101H	HLS 190IR
Wavelength range:	from 200 to 1100 nm	from 200 to 1100 nm	from 200 to 1100 nm	from 0.9 to 2.55 µm
Max. readout speed:	up to 500 kHz	up to 500 kHz	up to 1 MHz	up to 416 kHz
Sensor type:	CCD Back-Thinned	CCD Back-Thinned or Front-Illuminated	CCD Back-Thinned or Front-Illuminated	linear InGaAs
Number of pixels:	2048 x 64	from 2048 x 122 to 2048 x 506	from 1024 x 58 to 1024 x 1024	256 or 512
Pixel size (H) x (V):	14 x 14 µm	12 x 12 µm	24 x 24 µm	from 25 x 250 µm to 50 x 500 µm
Nominal value of the distance from a forward plane of the camera up to photosensitive field of the sensor:	10 mm	10 mm	10 mm	10 mm
Exposure time:	from 10 µs to 7.5 h	from 10 µs to 7.5 h	from 10 µs to 7.5 h	from 1 µs to 7.5 h
Analog-digital converter (ADC) of the cameras:	16 bit	16 bit	16 bit	16 bit















Thank you very much for your attention!